SPUTTERING TARGET MATERIAL FOR PRODUCING INTERMEDIATE LAYER FILM OF PERPENDICULAR MAGNETIC RECORDING MEDIUM AND THIN FILM PRODUCED BY USING THE SAME

ABSTRACT

There is disclosed a sputtering target material for producing an intermediate layer film of a perpendicular magnetic recording medium, which is capable of dramatically reducing the crystal grain size of a thin film formed by sputtering. The sputtering target material comprises, in at %, 1 to 20% of W; 0.1 to 10% in total of one or more elements selected from the group consisting of P, Zr, Si and B; and balance Ni.